

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Paul B. Mirkarimi et al.                      Docket No. : CIL-10972  
Serial No. : 10/086,614                                      Art Unit : 1762  
Filed : March 1, 2002                                      Examiner : A. Bashore  
For : Ion-Assisted Deposition Techniques for  
the Planarization of Topological Defects

PETITION FOR EXTENSION OF TIME UNDER 37 CFR 1.136(a)

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

This is a request under the provisions of 37 CFR 1.136(a) for a 3 month extension of the period for filing a reply in the above identified application.

If any impediments remain, please contact the undersigned at 808-875-0012.

Respectfully submitted,

/John P. Wooldridge #38,725/  
John P. Wooldridge  
Attorney for Applicant  
Registration No. 38,725

Dated: March 25, 2008